



Wednesday, May 16, 2012 (day two)

8:00-8:30 Registration

8:30-9:30 Keynote: R&D Perspective

Session 8 - Factory Optimization

Chairs: Sumita Basu, Intel Corporation; Paul Werbaneth,

Semiconductor equipment and manufacturing is increasingly complex and driven by strict economic constraints. It is vital for IC production to improve efficiency, control costs, and be good environmental stewards. This session covers novel solutions for environmental and material handling challenges.

9:35

8.1

Assessing the Impact of the 450mm Wafer Size Transition on Manufacturing Facility Automated Material Handling Systems

Larry Hennessy, CH2M HILL

10:00

8.2

Operator-Free Exception Measurement Logistics for a Highly Automated 200mm Semiconductor Manufacturing Environment

Andrea Bannert, Frank Heinlein, Matthias Adam, Infineon Technologies Dresden GmbH; Kay Manja, Systema GmbH

10:25 Break

10:45

8.3

Improving Eco-Efficiency via elimination of greenhouse gases from semiconductor dry cleaning processes

Chang Hyun Oh, Seung Jong Ko, and Yun Yeong Jeong, Hynix Semiconductor Inc.

11:10

8.4

Green Mode: Equipment Interface to Optimize Semiconductor SubFab Utility Consumption

Adrienne Pierce, Edwards Vacuum Inc.; Val Parks, GLOBALFOUNDRIES

11:35

8.5

Industry Approach to the Conflict Minerals legislation

Jared Connors, Intel Corporation

12:00 Boxed Lunch